

Applicant Initiated Interview Request Form

Application No.: 10/552,681 First Named Applicant: Roche Diagnostics Operations, Inc.
Examiner: Joel G. Horning Art Unit: 1792 Status of Application: Pending

Tentative Participants:

(1) Attorney Timothy N. Thomas (2) Examiner Joel G. Horning
(3) _____ (4) _____

Proposed Date of Interview: February 24, 2010 Proposed Time: 1:30 PM AM/PM

Type of Interview Requested:

(1) ☒ Telephonic (2) ☐ Personal (3) ☐ Video Conference

Exhibit To Be Shown or Demonstrated: ☐ YES ☒ NO

If yes, provide brief description: _____

Issues To Be Discussed

Issues (Rej., Obj., etc)	Claims/ Fig. #s	Prior Art	Discussed	Agreed	Not Agreed
(1) <u>12</u>	_____	<u>Wojnarowski et al US 5,302,547</u>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>
(2) _____	_____	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
(3) _____	_____	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
(4) _____	_____	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

☒ Continuation Sheet Attached

Brief Description of Argument to be Presented:

Please See Attached Sheet

An interview was conducted on the above-identified application on _____.

NOTE: This form should be completed by applicant and submitted to the examiner in advance of the interview (see MPEP § 713.01).

This application will not be delayed from issue because of applicant's failure to submit a written record of this interview. Therefore, applicant is advised to file a statement of the substance of this interview (37 CFR 1.133(b)) as soon as possible.

Applicant/Applicant's Representative Signature
Timothy N. Thomas

Typed/Printed Name of Applicant or Representative
35714

Examiner/SPE Signature

Registration Number, if applicable

This collection of information is required by 37 CFR 1.133. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to take 21 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

Re: United States Patent Application No. 10/552,681
Filing Date: February 28, 2007
Title: METHOD FOR PRODUCING MULTIPLE LAYER
SYSTEMS
Inventor(s): Meier, Bhullar
Our Ref.: 007404-000740

Applicants' claim 12 includes the limitation that an intermediate, "sacrificial" layer is used to selectively remove an adjacent non-conductive or metallic layer. In particular, a sacrificial layer (such as an organic polymer layer) is deposited adjacent a dielectric layer and photon energy is introduced into the sacrificial layer to ablate the sacrificial layer and thereby to remove either the non-conductive layer above or the metallic layer below. Applicants believe that that feature is neither taught nor suggested by Wojnarowski.

The pending Office Action appears to contend that Wojnarowski discloses applying energy to a sacrificial layer to remove either a non-conductive layer above or a metallic layer below. In particular, the Office Action appears to contend that Wojnarowski provides a non-conductive layer 76 adjacent an intermediate sacrificial (bi)layer 18/20, and uses laser energy to ablate the intermediate (bi)layer 18/20, thus removing the non-conductive layer 76.

Applicants' review of the Wojnarowski '547 patent suggests that the Wojnarowski non-conductive layer is removed by ablating it directly, and not by the ablation of an adjacent "sacrificial" layer. Wojnarowski discloses a non-conductive layer that overlies a dielectric layer, and Wojnarowski teaches that "[t]he nitride film is removed at the same time and in the same area during the laser ablation of second dielectric layer 20." Wojnarowski '547 at col. 7, lines 60-63. This appears to disclose using a laser to ablate both layers directly, rather than ablating only the intermediate/sacrificial layer and causing the non-conductive layer to be removed as a consequence of that ablation of the dielectric layer.